



A. Interconnect & Package 분과

2019년 2월 14일(목), 11:00-12:30

Room E (스카이홀, 2층)

[TE2-A] Interconnect & Package

좌장: 이후정 교수(성균관대학교), 최광성 박사(ETRI)

<p>TE2-A-1 11:00-11:30</p>	<p>[초청] Studies on Electronic Materials in Recent Advanced Packaging : Package Level EMI Shielding Pastes and Core/Shell Fillers Seyoung Jeong,¹ Kisu Joo¹, Taeryong Kim², Kyu Jae Lee¹, and Jung Woo Hwang¹ ¹Ntrium Incorporation, ²Department of Materials Science and Engineering, Seoul National University</p>
<p>TE2-A-2 11:30-11:45</p>	<p>Tungsten Thin Film Grown by Plasma-Enhanced Atomic Layer Deposition Using Fluorine Free Precursor Hwi Yoon¹, Seunggi Seo¹, Yujin Lee¹, Bonggeun Shong², Kyu-Hyun Yeom³, Jungwon Hwang³, Jang Hyeon Seok³, Jung Woo Park³, and Hyungjun Kim¹ ¹School of Electrical and Electronic Engineering, Yonsei University, ²Department of Chemical Engineering, Hongik University, ³Hansol Chemical</p>
<p>TE2-A-3 11:45-12:00</p>	<p>피치 변화에 따른 테스트 프로브 핀의 등가회로 영향 분석 Cheolhong Park, Moonjung Kim Department of Electrical Electronic and Control Engineering, Kongju National University</p>
<p>TE2-A-4 12:00-12:15</p>	<p>Thermal Stability and Endurance of Nitrogen-Doped SiTe Ovonic Threshold Switch Jeongun Choe^{1,2}, Deok-Jin Jeon^{1,2}, Jihye Lee^{1,2}, JaeHyun Kang^{1,2}, and Jong-Souk Yeo^{1,2} ¹School of Integrated Technology, Yonsei University, ²Yonsei Institute of Convergence Technology, Yonsei University</p>
<p>TE2-A-5 12:15-12:30</p>	<p>Screening of Reducing Agent for Atomic Layer Deposition of Tungsten Using WCl₅: Density Functional Theory Study Romel Hidayat¹, 김성윤¹, 김수현², 이원준¹ ¹세종대학교 나노신소재공학과, ²영남대학교 신소재공학과</p>